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PATENT

Attorney Docket No.  
033082 M 274

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of: ) **CONFIRMATION NO.: 3704**

Kazuhide HASEBE, et al. )

U.S. Serial No.: 10/549,851 ) Group Art Unit: 2812

Filed: September 23, 2005 ) Examiner: Reema Patel

For: METHOD FOR CLEANING FILM-FORMING UNIT

**RESPONSE TO RESTRICTION REQUIREMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir :

A response to the Office Action mailed May 14, 2007 is due by June 14, 2007. The Action required restriction among the following:

Group I of claims 1, 4, 6-11, 12, 15, and 16-20,

Group II of claims 2, 6-11, 13, and 16-20, and

Group III of claims 3, 6-11, 14, and 16-20.

Applicants hereby elect Group I of claims 1, 4, 6-11, 12, 15, and 16-20, drawn to a cleaning method and apparatus which involve a nitrogen-including gas being activated to nitride the surface of a reaction chamber, for examination in this application.

Applicants reserve the right to file divisional application(s) for the non-elected claims in due course.

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It is submitted that this application now is in condition for examination on the merits and early action in that regard is solicited.

Respectfully submitted,  
SMITH, GAMBRELL & RUSSELL, LLP



Michael A. Makuch – Registration No. 32,263  
1850 M Street, NW – Suite 800  
Washington, DC 20036  
Tel : 202 263 4300  
Fax : 202 263 4329

Date : June 8, 2007